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TRANSMITTAL FORM

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Total Number of Pages in This Submission

Application Number	10/087,040
Filing Date	February 28, 2002
First Named Inventor	Miller, David et al.
Group Art Unit	Unassigned
Examiner Name	Unassigned
Total Number of Pages in This Submission	1
Attorney Docket Number	19930-002800

ENCLOSURES (check all that apply)

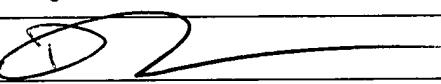
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<input type="checkbox"/> Certified Copy of Priority Document(s)	<input type="checkbox"/> CD, Number of CD(s)	3. 26 References
<input type="checkbox"/> Response to Missing Parts/ Incomplete Application	Remarks	The Commissioner is authorized to charge any additional fees to Deposit Account 20-1430.
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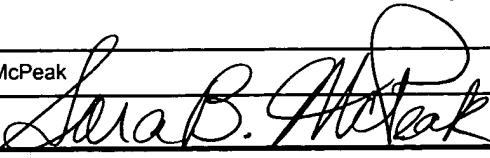
SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm and Individual name	Townsend and Townsend and Crew LLP Douglas M. Hamilton	Reg. No. 47,629
Signature		
Date	May 6, 2002	

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PATENT

Attorney Docket No.: 19930-002800

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

David Miller et al.

Application No.: 10/087,040

Filed: February 28, 2002

For: SYSTEMS AND METHODS FOR
OVERCOMING STITION

Examiner: Unassigned

Art Unit: Unassigned

**INFORMATION DISCLOSURE
STATEMENT UNDER 37 CFR §1.97 and
§1.98**

Assistant Commissioner for Patents
U. S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

The references cited on attached form PTO-1449 are being called to the attention of the Examiner. Copies of the references are enclosed. It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

Applicant believes that no fee is required for submission of this statement, since it is being submitted prior to the first Office Action. However, if a fee is required, the Commissioner is authorized to deduct such fee from the undersigned's Deposit Account No. 20-1430. Please deduct any additional fees from, or credit any overpayment to, the above-noted Deposit Account.

Respectfully submitted,

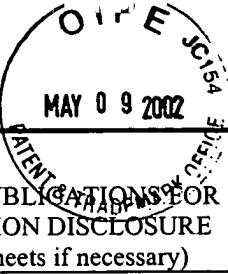


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FORM PTO-1449 (Modified)

LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE
STATEMENT (Use several sheets if necessary)

Attorney Docket No.: 19930-002800US

Application No.: 10/087,040

Applicant: David Miller et al.

Filing Date: February 28, 2002

Group: Unassigned

<input type="checkbox"/> AZ	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202
<input type="checkbox"/> BA	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 6, June 1995
<input type="checkbox"/> BB	P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704
<input type="checkbox"/> BC	Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998
<input type="checkbox"/> BD	Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000
<input type="checkbox"/> BE	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and do not consider. Include copy of this form with next communication to applicant.

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FORM PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	Attorney Docket No.: 19930-002800US		Application No.: 10/087,040
	Applicant: David Miller et al.		
	Filing Date: February 28, 2002		Group: Unassigned

Reference Designation		U.S. PATENT DOCUMENTS				Page 1
Examiner Initial	Document No.	Date	Name	Class	Sub-class	Filing Date (If Appropriate)
AA	5,414,540	05/09/95	Patel et al.	359	39	
AB	5,917,625	06/29/99	Ogusu et al.	359	130	
AC	5,999,672	12/07/99	Hunter et al.	385	37	
AD	6,028,689	02/22/00	Michalicek et al.	359	224	
AE	6,040,935	03/21/00	Michalicek	359	198	
AF	6,097,859	08/01/00	Solgaard'	385	17	
AG	6,108,471	08/22/00	Zhang et al.	385	37	
AH	6,128,122	10/03/00	Drake et al.	359	224	
AI	09/442,061		Weverka, et al.			11/16/99
AJ						
AK						

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FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
AL						
AM						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AN	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110
AO	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978
AP	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992
AQ	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96
AR	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999
AS	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100
AT	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65
AU	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987
AV	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985
AW	P. Phillippe et al., "Wavelength demultiplexer: using echelle gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985
AX	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986
AY	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998